IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant(s): PYO, Sung Gyu et al.

Application No.:

Group:

Filed:

May 30, 2002

Examiner:

For:

CU FILM DEPOSITION EQUIPMENT OF SEMICONDUCTOR DEVICE

LETTER

Assistant Commissioner for Patents Box Patent Application Washington, D.C. 20231



Sir:

Under the provisions of 35 USC 119 and 37 CFR 1.55(a), the applicant hereby claims the right of priority based on the following application(s):

Filed Application No. Country

P 2001-32907 06/12/01 REPUBLIC OF KOREA

A certified copy of the above-noted application(s) is(are) attached hereto.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. 1.16 or under 37 C.F.R. 1.17; particularly, extension of time fees.

> Respectfully submitted, BIRCH, STEWART, KOLASCH & BIRCH, LLP

By:

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TYU, Sur Howet ac. Man 30, 2002 BSKB-103/205-800C Docket 90, 0465-08657 1931

대 한 민 국 특 허

KOREAN INTELLECTUAL PROPERTY OFFICE



별첨 사본은 아래 출원의 원본과 동일함을 증명함.

This is to certify that the following application annexed hereto is a true copy from the records of the Korean Intellectual Property Office.

워 亨 특허출원 2001년 제 32907 호

Application Number

워 년 월 2001년 06월 12일

Date of Application

원

출

인 :

주식회사 하이닉스반도체

Applicant(s)



2001

